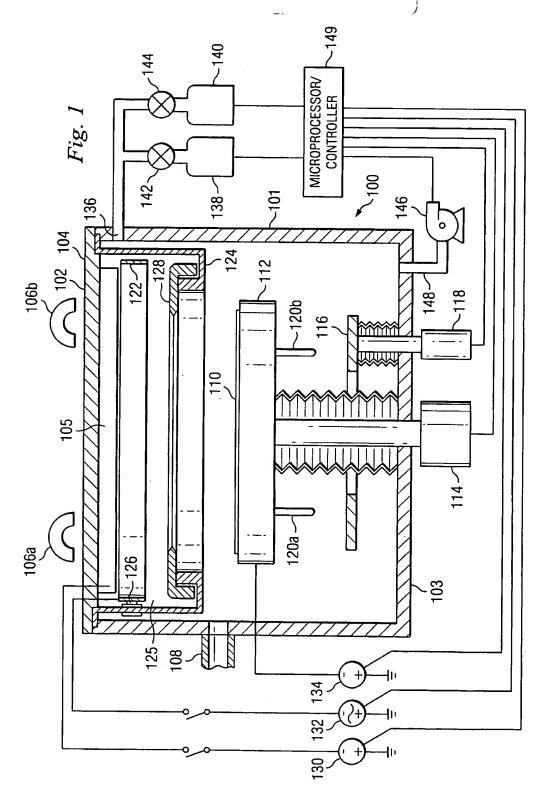
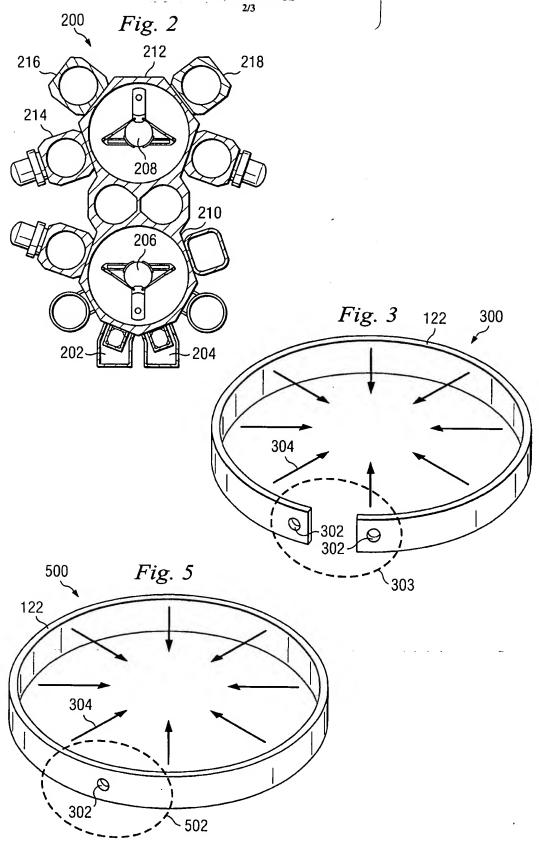
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Serial No. N/A/ - 24061.30 Cho et al. RF COIL DESIGN FOR IMPROVED FILM UNIFORMITY OF AN ION METAL PLASMA SOURCE 2/3



## Serial No. N/A/ – 24061.30 Cho et al. RF COIL DESIGN FOR IMPROVED FILM UNIFORMITY OF AN ION METAL PLASMA SOURCE 3/3

